

PTO/SB/08A (08-03)

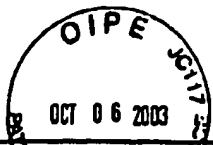
substitute for form 1449 A/PTO			Complete If Known		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)			Application Number	10/632,662	
			Filing Date	August 1, 2003	
			First Named Inventor	Staple, Bevan	
			Art Unit		
			Examiner Name		
Sheet	1	of	3	Attorney Docket Number	019930-003110US

U.S. PATENT DOCUMENTS+					
Examiner Initials*	Cite No. ¹	Document Number Number Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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Examiner Signature	<i>Michelle R. Connolly-Cuthwa</i>	Date Considered	3/4/04
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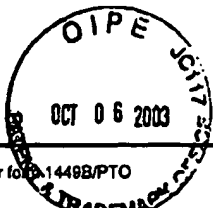
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		Attorney Docket Number	019930-003110US

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
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Examiner Signature	<i>Michael R. Connelly-Curtis</i>	Date Considered	3/4/04
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Examiner Signature	<i>Michelle R Connolly-Kurba</i>	Date Considered	3/4/04
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